



09-01-03

2814#

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Ajit P. Paranjpe et al.  
Serial No.: 09/864,714  
Filing Date: May 23, 2001  
Group Art Unit: 2814  
Examiner: Rao, Shrinivas H.  
Title: *Atomic Layer Deposition For Fabricating Thin Films*

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marsha  
5/7/03

**Box: Amendments – Fee**

Commissioner for Patents  
Washington, D.C. 20231

I hereby certify that this correspondence is being deposited with the United States Postal Service as Express Mail No. EV230875516US in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on the date shown below.

Shannon Judice  
Shannon Judice

4/30/03  
Date of Signature

**RESPONSE TO OFFICE ACTION**

Dear Sir:

In response to the Office Action mailed January 15, 2003 (Paper No. 6), Applicants respectfully request that the Examiner reconsider application in view of the following amendments and remarks. The amendments are formatted and presented in accordance with the Revised Format for Amendments promulgated earlier in 2003 by the U.S. Patent and Trademark Office.

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